



Compound Semiconductor Materials Japan TC Chapter Meeting

In conjunction with SEMICON Japan 2025

Thursday, December 18, 2025

Room 907, TFT Building East Wing 9F, Tokyo, Japan/ Official Virtual TC Chapter Meeting (Hybrid)

2:00 PM – 4:00 PM JST

AGENDA

1 Welcome/Call to Order

- 1.1 Introduction
- 1.2 Required Elements (Membership Requirements, Antitrust and Intellectual Property Reminders, and Effective Meeting Guidelines)
- 1.3 Agenda Review

2 Review of Previous Meeting Minutes

3 Technical Committee Award

4 Liaison Report

- 4.1 Japan Regional Standards Committee (JRSC)
- 4.2 Global Coordinating Subcommittee (GCS)
- 4.3 Europe TC Chapter
- 4.4 North America TC Chapter
- 4.5 China TC Chapter

5 Staff Report

6 Ballot Review

7 Subcommittee & Task Force Reports

- 7.1 Silicon Carbide Substrate Liaison Task Force
- 7.2 SiC Epitaxial Wafer Liaison Task Force



8 Old Business

8.1 Project Period Review

8.2 5-year Review

9 New Business

9.1 TFOF for SiC Material and Wafer Task Force

9.2 Leadership Change

10 Action Item Review

10.1 Open Action Items

<i>Item #</i>	<i>Assigned to</i>	<i>Details</i>
CSM_20250630-01	SEMI Staff	To forward ballot review results of Doc.#7211A to the ISC A&R SC for procedural review.
CSM_20250630-02	TC members	To discuss the remaining issues of SiC Epitaxial Wafer.

10.2 New Action Items

<i>Item #</i>	<i>Assigned to</i>	<i>Details</i>

11 Next Meeting and Adjournment

11.1 The next meeting is scheduled for <date> at <event/location>.